

HALO-02-003



January 5, 2004

To: Commissioner for Patents
P.O.Box 1450
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572
28 Davis Avenue
Poughkeepsie, N.Y. 12603

Subject: | Serial No. 10/685,873 10/15/03 |

Seiki Ogura et al.

TWIN INSULATOR CHARGE STORAGE
DEVICE OPERATION AND ITS FABRICATION
METHOD

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation
In An Application.

The following Patents and/or Publications are submitted to
comply with the duty of disclosure under CFR 1.97-1.99 and
37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being
deposited with the United States Postal Service as first class
mail in an envelope addressed to: Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450, on January 27, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

 1/27/04

The following two articles discuss when the bottom oxide is as thin as or less than 23 Angstroms, holes are injected by a direct tunneling mechanism and the electron negative charge is neutralized by the holes:

- 1) S. Minami et al., "A Novel MONOS Nonvolatile Memory Device Ensuring 10-Year Data Retention after 10 to the 7th power Erase/Write Cycles," IEEE Trans. on Electron Device, Vol. 40, No. 11, Nov. 1993, pp. 2011-2017.
- 2) E. Suzuki et al., "Hole and Electron Current Transport in Metal-Oxide-Nitride-Oxide-Silicon Memory Structures," IEEE Trans. on Electron Device, Vol. 36, No. 6, June 1989, pp. 1145-1149.

T.Y. Chan et al., "A True Single-Transistor Oxide-Nitride-Oxide EEPROM Device", IEEE Electron Device Letters, Vol. EDL-8, No.3, March, 1987, describes a novel single-transistor EEPROM device using single-polysilicon technology.

Kuo-Tung Chang et al., "A New SONOS Memory Using Source-Side Injection for Programming", IEEE Electron Device Letters, Vol. 19, No. 7, July, 1998, discusses a new polysilicon-oxide-nitride-oxide-silicon (SONOS) nonvolatile memory using channel hot electron injection for high-speed programming.

The article by Paulo Cappelletti et al., "Flash Memories," Kluwer Academic Publishers 1999, pp. 217-223, discusses how hot hole injection is notorious for damaging oxide through injection because its effective mass is three times larger than an electron's.

U.S. Patent 6,255,166 to Ogura et al., "Nonvolatile Memory Cell, Method of Programming the Same and Nonvolatile Memory Array," provides a high speed and low program voltage nonvolatile memory cell, a programming method for same and a nonvolatile memory array.

U.S. Patent 6,469,935 to Hayashi, "Array Architecture Nonvolatile Memory and Its Operation Methods," discusses how a nonvolatile memory array architecture can be realized by a fabrication process more compatible to an MOS logic fabrication process as compared with previous nonvolatile memory array architectures.

U.S. Patent 6,531,350 to Satoh et al., "Twin MONOS Cell Fabrication Method and Array Organization," describes a fabricating method and its array organization for a high-density twin MONOS memory device integrating a twin MONOS memory cell array and CMOS logic device circuit.

U.S. Patent 6,498,377 to Lin et al., "SONOS Component Having High Dielectric Property," describes a MONOS cell structure where nitride storage lies under sidewall spacers.

U.S. Patent 6,356,482 to Derhacobian et al., "Using Negative Gate Erase Voltage to Simultaneously Erase Two Bits from a Non-Volatile Memory Cell with an Oxide-Nitride-Oxide (ONO) Gate Structure," teaches applying a negative gate erase voltage to improve erase after many program-erase cycles.

U.S. Patent 6,040,995 to Reisinger et al., "Method of Operating a Storage Cell Arrangement," discloses F-N tunneling erase of nitride through a thick oxide layer.

U.S. Patent 5,408,115 to Chang, "Self-Aligned, Split-Gate EEPROM Device," discusses F-N tunneling erasure through the top oxide wherein the bottom oxide is thick.

Sincerely,



Stephen B. Ackerman,
Reg. No. 37761

<p style="text-align: center;">P E INFORMATION DISCLOSURE CITATION IN AN APPLICATION</p> <p>29 2004 (Use several sheets if necessary)</p>				Document Number (Optional) HALO-02-003	Application Number 10/685,873	
				Applicant Seiki Ogura et al.		
				Filing Date 10/15/03	Group Art Unit	
U. S. PATENT DOCUMENTS						
DATE OF EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	PLACING DATE IF APPROPRIATE
	6 2 551 667 3/01	Ogura et al.	438	257		12/28/99
	6 4 699 35 10/22/02	Hayashi	365	185.18		3/19/01
	6 531 350 3/11/03	Satoh et al.	438	197		11/21/01
	6 4 983 77 12/24/02	Lin et al.	257	411		3/21/02
	6 3 564 823 12/02	Derhacobian et al.	365	185.29		9/7/00
	6 0 409 95 3/21/00	Reisinger et al.	365	185.18		7/29/97
	5 40811 54/18/95	Chang	257	324		4/4/94
FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation YES NO
OTHER DOCUMENTS (Including Author, Title, Date, Page or Pages, Etc.)						
-	S. Minami et al., "A Novel MONOS Nonvolatile Memory Device Ensuring 10-Year Data Retention after 10 ⁷ Erase/Write Cycles", <u>IEEE Trans. on Electron Device</u> , Vol. 40, No. 11, Nov. 1993, pp. 2011-2016.					
-	E. Suzuki et al., "Hole and Electron Current Transport in Metal-Oxide-Nitride-Oxide-Silicon Memory Structures", <u>IEEE Trans. on Electron Device</u> , Vol. 36, No. 6, June 1989, pp. 1145-1149.					
EXAMINER	DATE CONSIDERED					

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

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-	T-Y. Chan et al., "A True Single-Transistor Oxide-Nitride-Oxide EEPROM Device", IEEE Electron Device Letters, Vol. EDL-8, No. 3, March 1987.					
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METHOD

ASSOCIATE POWER OF ATTORNEY

I hereby appoint Rosemary L.S. Pike, registration number 39,332, as my associate attorney in this case. Her telephone number is (765) 453-0866.

Please continue to direct all correspondence in this case to the undersigned attorney.

Respectfully submitted,

Stephen B. Ackerman,

Principal attorney of record